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Abstract

PROBLEM TO BE SOLVED: To provide a glass substrate storage jig for CVD and ALE apparatuses which prevents the film forming gas from infiltrating a back side of the glass substrate and the glass substrate from being cracked or chipped.

SOLUTION: The glass substrate storage jig 20 for CVD and ALE apparatuses comprises a back side support portion 21 to support a back side of the glass substrate 10, an upper cover portion to support four sides of the glass substrate, a lower support portion 23 and right and left sides support portions 24, and at least the lower support portion located downstream of the gas flow has a holding wall 25 to cover a lower surface. An end 26 of the holding wall not in contact with the glass substrate is formed streamline. A space between the back side support portion to hold the glass substrate and the holding wall is variable.